

Appl. No. 10/669,671

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.10/669,671
Filing Date September 23, 2003
Inventor..... Neal R. Rueger et al.
Assignee.....Micron Technology, Inc.
Group Art Unit.....2823
ExaminerKebede, Brook
Attorney's Docket No.MI22-2145
Customer No.021567
Title: Methods of Filling Gaps and Methods of Depositing Materials Using High Density
Plasma Chemical Vapor Deposition

RESPONSE TO DECEMBER 13, 2005 FINAL OFFICE ACTION

To: Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)
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AMENDMENTSIntroductory Comments

In reply to the Final Office Action of December 13, 2005, applicant amends and
remarks as follows.

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